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JAPANESE PATENT OFFICE

PATENT ABSTRACTS OF JAPAN

(11) Publication number: 61082649 A

(43) Date of publication of application: 26.04.86

(51) Int. Cl

H01J 49/06

H01L 41/00

// G01B 7/14

G01N 27/62

(21) Application number: 59205154

(22) Date of filing: 29.09.84

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(54) SLIT MECHANISM

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(57) Abstract:

PURPOSE: To simplify a structure of the captioned slit mechanism and operation externally of a vacuum chamber with ease by connecting a movable slit piece for forming the slit to a bimorph type piezo-electric element 10, and applying voltage in response to a slit width to displace it.

CONSTITUTION: A slit mechanism for use in a mass spectrometer, etc., is mounted by fitting the tip end of a bimorph type piezo-electric element 10 into a groove 8, while a position sensor 14 being a photointerrupter is provided between slits. Said bimorph type piezo-electric element is constructed by forming the slit S with use of a pair of slit pieces 2, 6 fixing the slit piece 2 on a supporter 4, and fixing a base end part of the slit piece 6 on the supporter 4 by means of a clumper 12. Voltage applied to the bimorph type piezo-electric element 10 is controlled by a signal from the sensor 14 to set a prescribed slit width. Accordingly, the slit mechanism can be adjusted only by delivering an electric signal into the vacuum chamber, and its structure can greatly be simplified.

